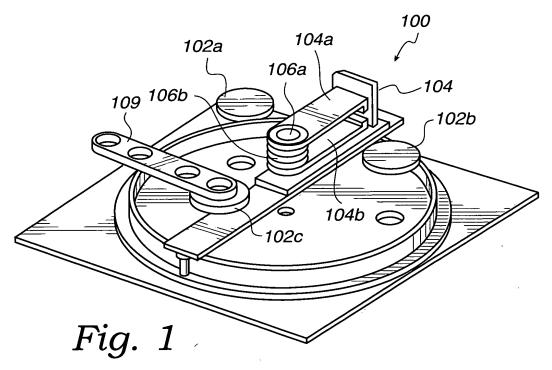
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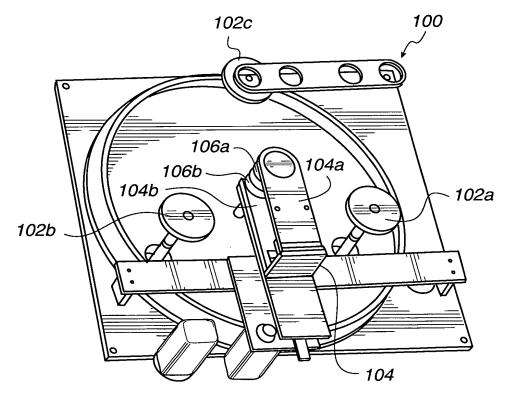
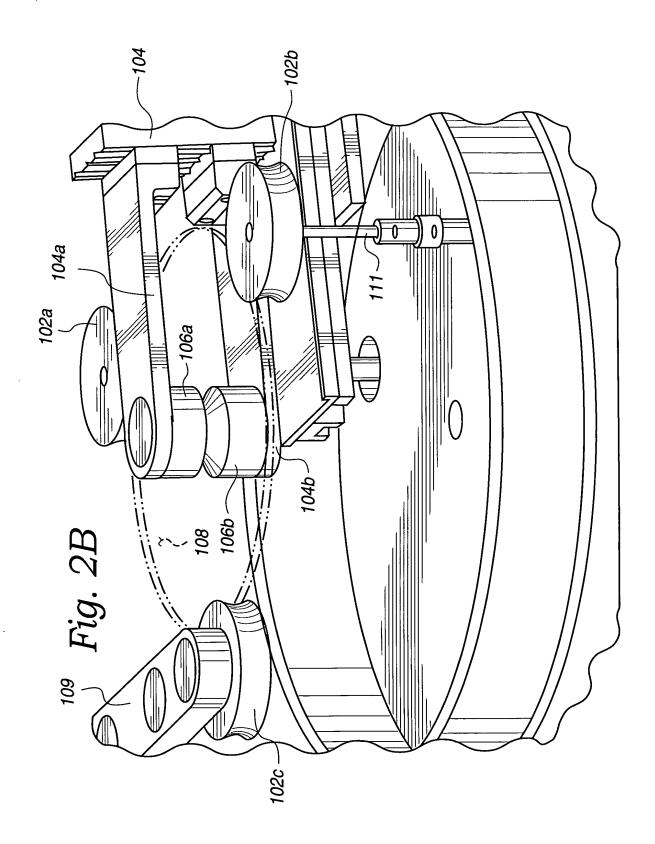
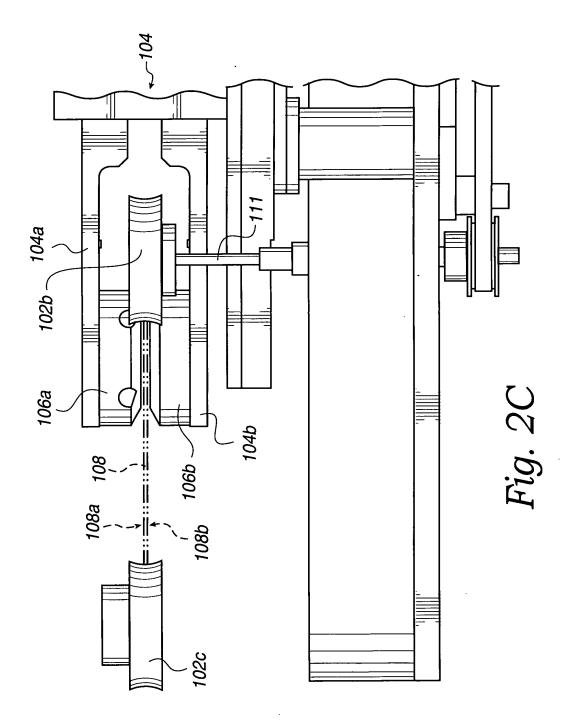


Fig. 2A

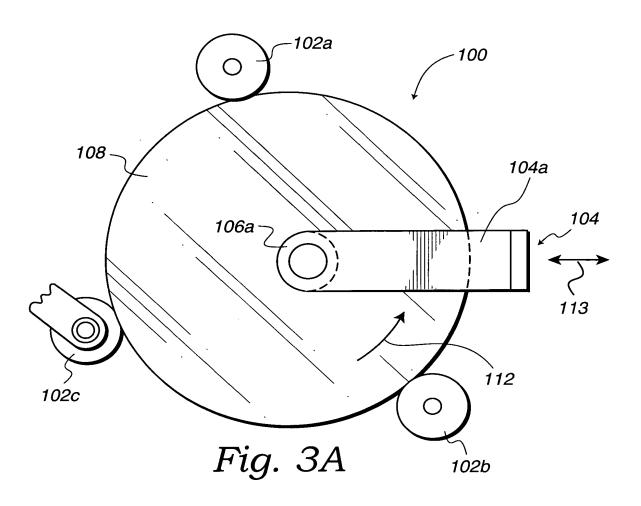
Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process
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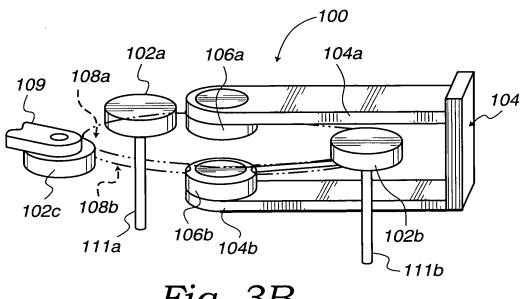


Fig. 3B

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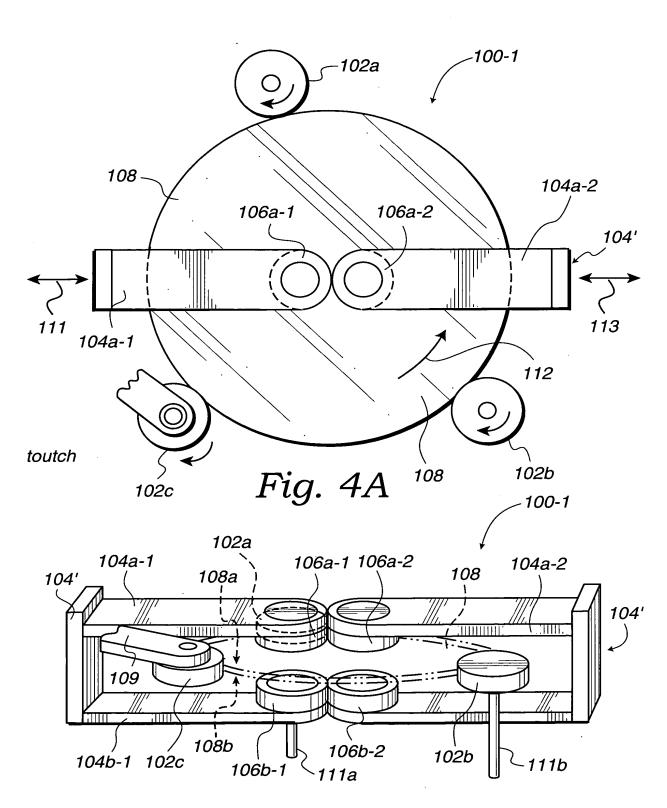
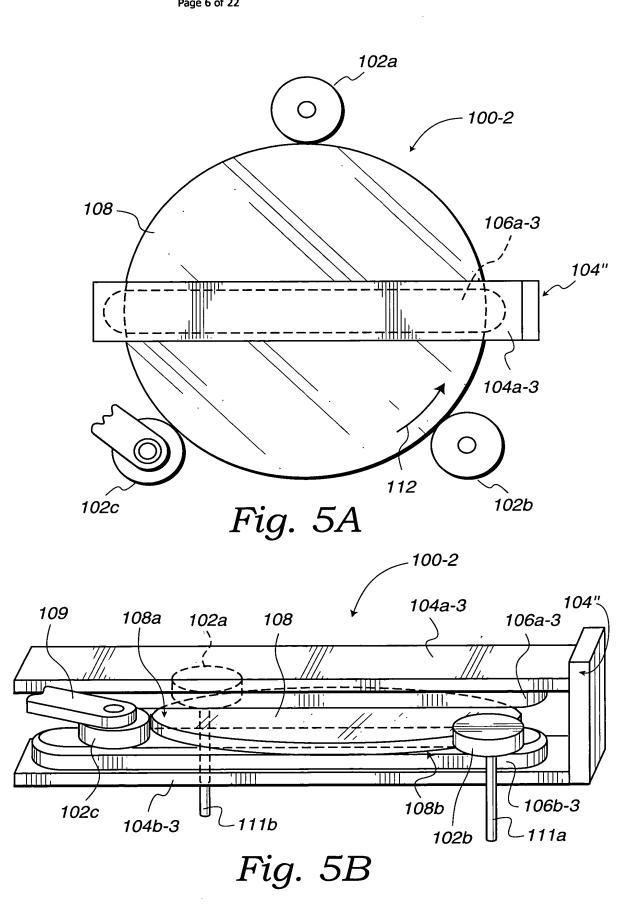
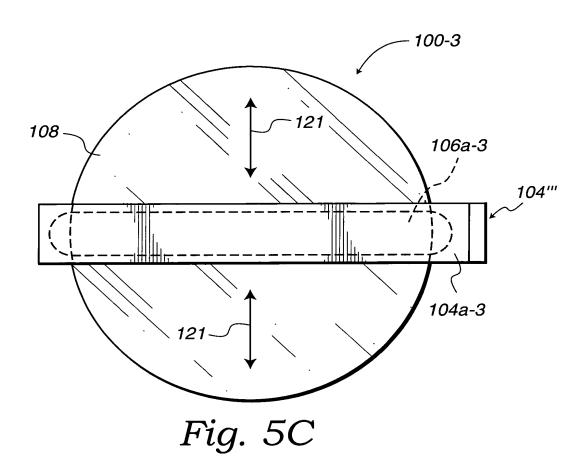


Fig. 4B

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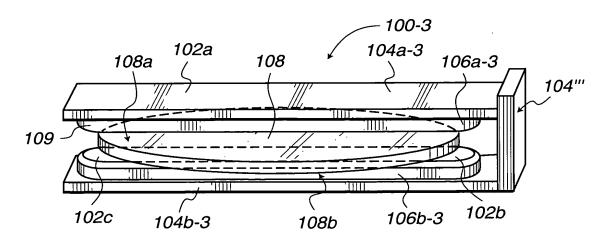
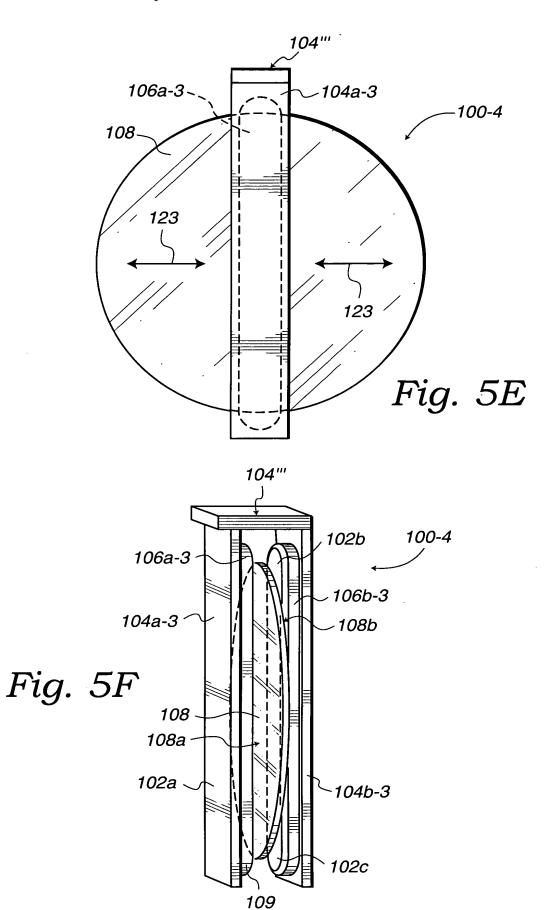
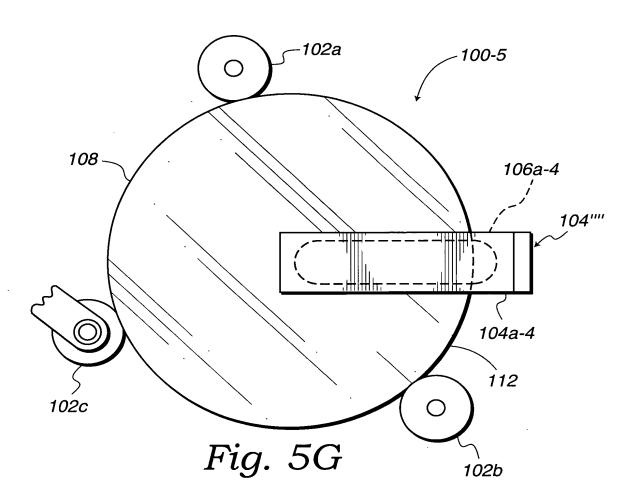


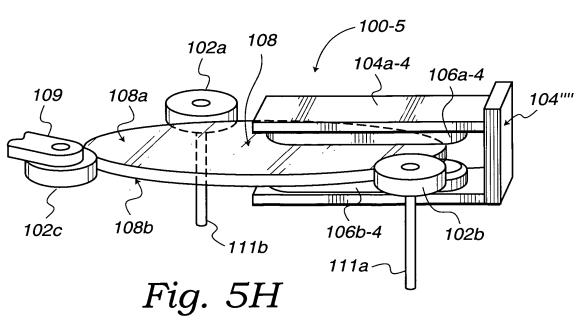
Fig. 5D

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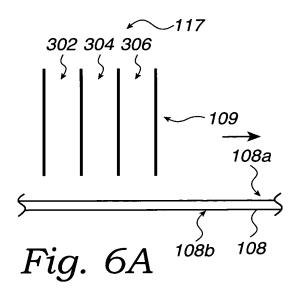


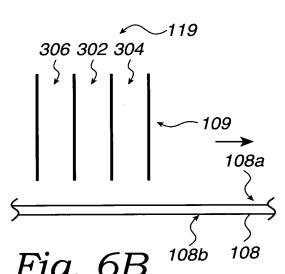


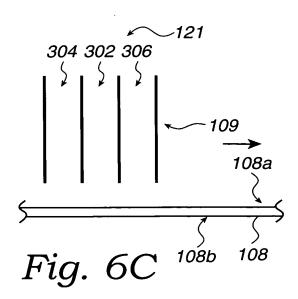
Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process

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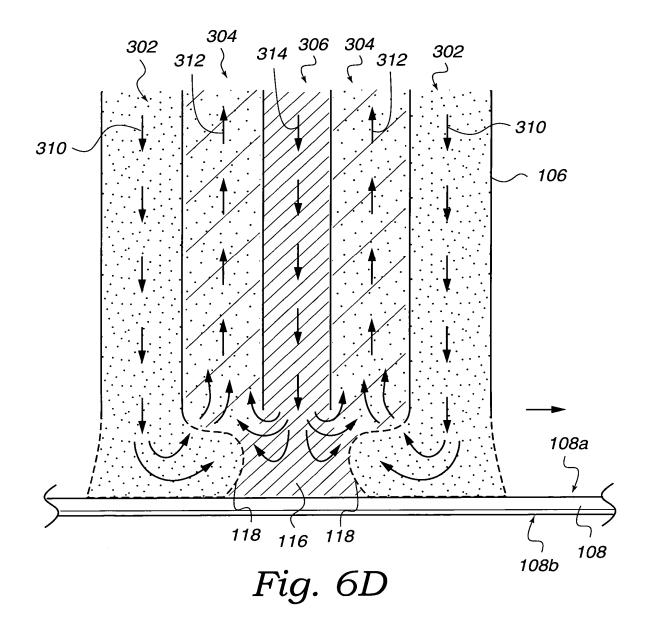






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Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process Application No: 10/606,022 File No: LAM2P425 Inventor: BOYD et al. Page 12 of 22

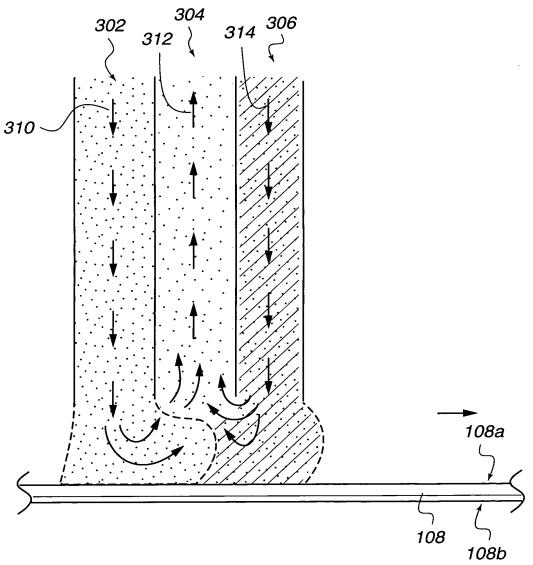
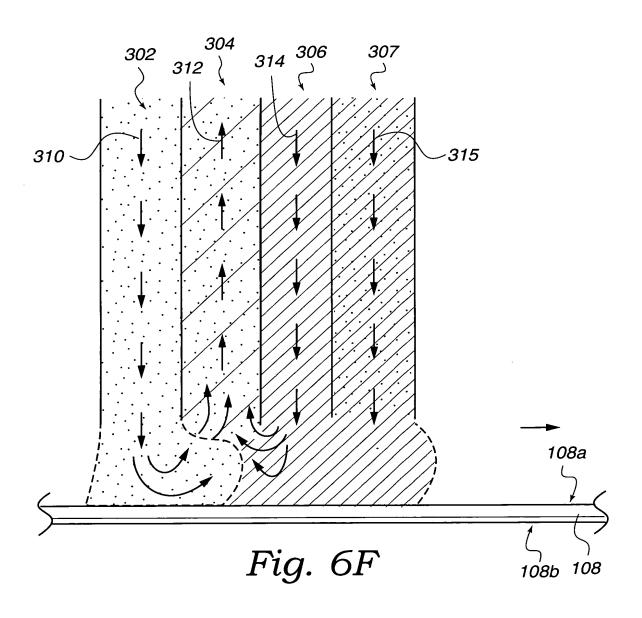


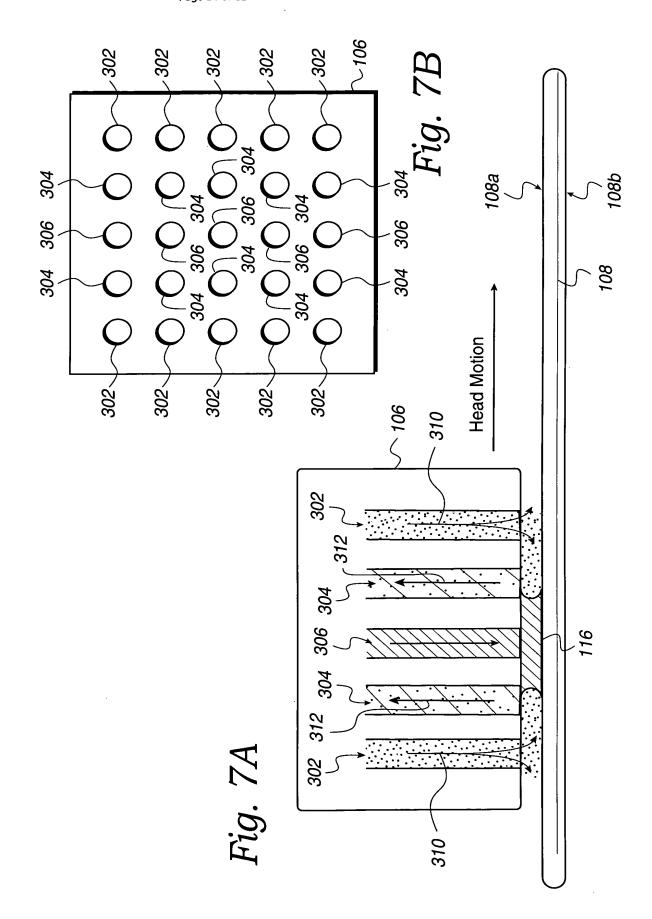
Fig. 6E

Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process Application No: 10/606,022 File No: LAM2P425 Inventor: BOYD et al. Page 13 of 22



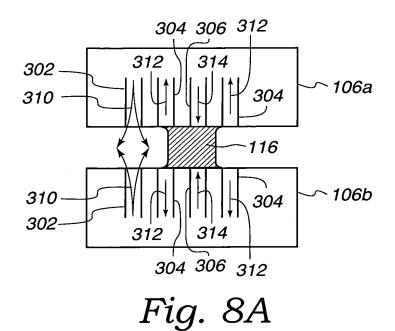
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Metrology Within A Wafer Process Application No: 10/606,022 File No: LAM2P425 Inventor: BOYD et al. Page 15 of 22



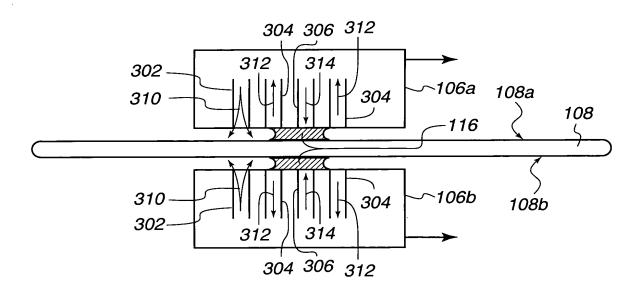


Fig. 8B

Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process Application No: 10/606,022 File No: LAM2P425

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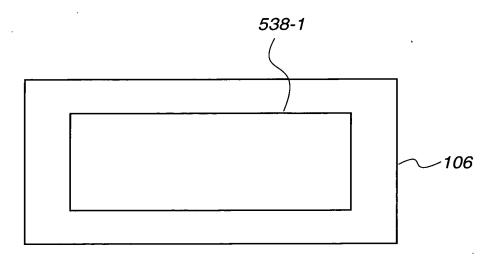


Fig. 9A

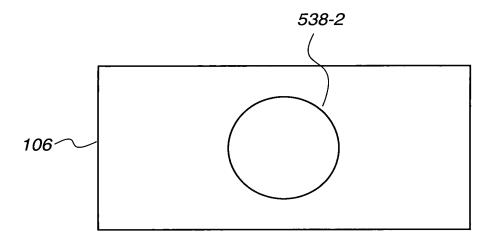


Fig. 9B

Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process Application No: 10/606,022 File No: LAM2P425 Inventor: BOYD et al. Page 17 of 22

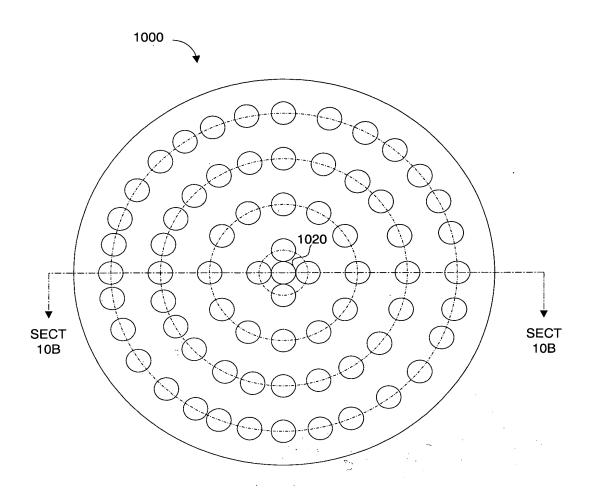


FIGURE 10A

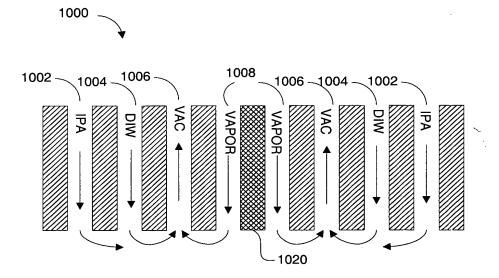


FIGURE 10B

Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process Application No: 10/606,022 File No: LAM2P425 Inventor: BOYD et al. Page 18 of 22

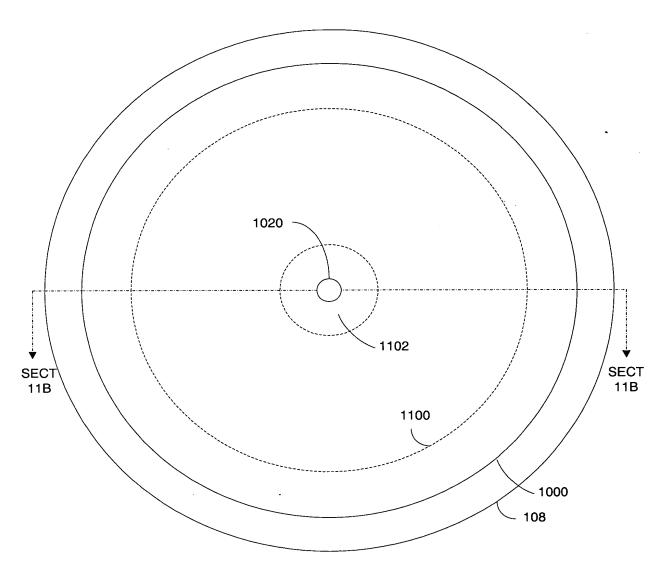
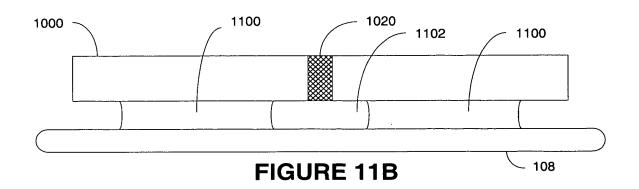


FIGURE 11A



Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process Application No: 10/606,022 File No: LAM2P425 Inventor: BOYD et al. Page 19 of 22

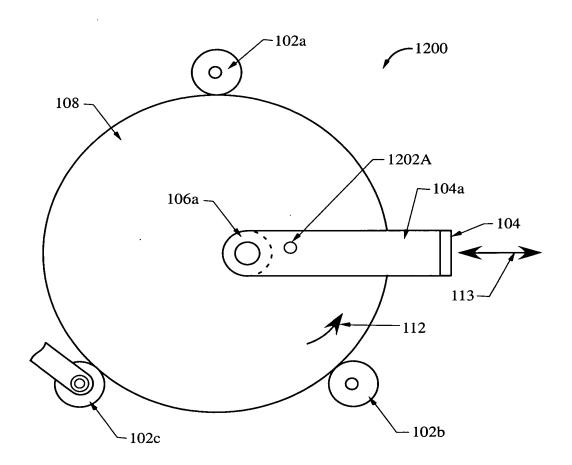


FIGURE 12A

Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process Application No: 10/606,022 File No: LAM2P425 Inventor: BOYD et al. Page 20 of 22

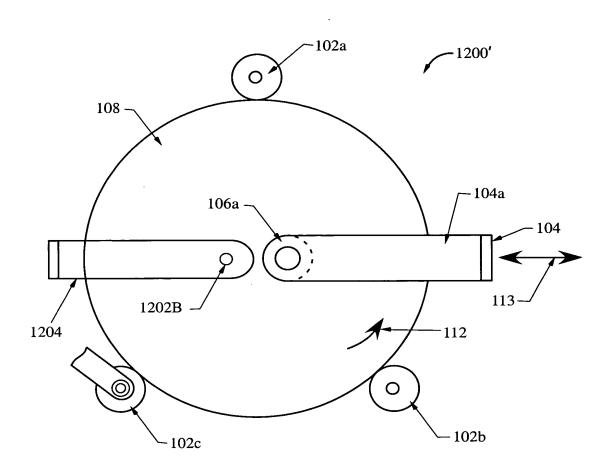
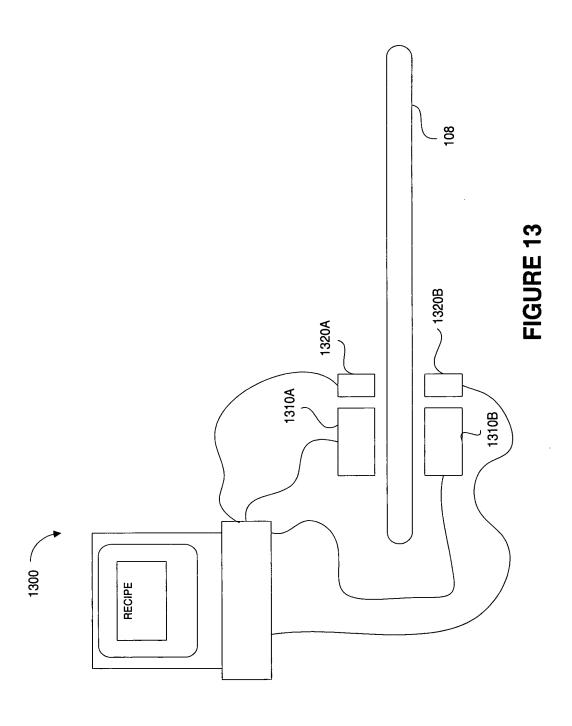


FIGURE 12B

Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process Application No: 10/606,022 File No: LAM2P425 Inventor: BOYD et al. Page 21 of 22



Title: System and Method For Integrating In-Situ Metrology Within A Wafer Process Application No: 10/606,022 File No: LAM2P425 Inventor: BOYD et al.

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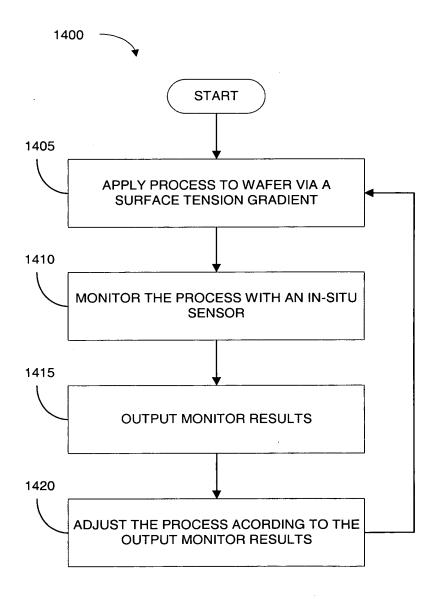


FIGURE 14